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503.30414V20

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

KATO, et al.

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Serial No.:

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METHOD THEREFOR

SUPPLEMENTING INFORMATION DISCLOSURE STATEMENT 37 CFR §1.97 & §1.98

Assistant Commissioner of Patents Washington, D.C.

July 6, 200

Sir:

The undersigned notes the Information Disclosure Statement submitted May 29, 2001, in connection with the above-identified application. An English-language abstract was submitted together with Japanese Patent Document No. 63-133521 enclosed with this Information Disclosure Statement.

To further facilitate consideration by the Examiner of Japanese Patent Document No. 63-133521, enclosed please find an English translation of this Japanese Patent Document No. 63-133521.

Particularly in view of the present submission of this English translation, and noting that there has not yet been a first Office Action on the merits in the above-identified application, full consideration of Japanese Patent Document No. 63-133521, upon examination of the above-identified application, is respectfully requested.

Please charge any shortage in fees due in connection with the filing of this paper to the Deposit Account No. 01-2135

(Case No. 503.30414V20) and please credit any excess fees to such Deposit Account.

Respectfully submitted,

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